TT-2 AFM

THIS COMPACT **SECOND GENERATION** TABLETOP ATOMIC FORCE MICROSCOPE HAS ALL THE IMPORTANT FEATURES AND BENEFITS EXPECTED FROM A LIGHT LEVER AFM.

FOR

- **Scientists & Engineers**

  Wanting a modular AFM for scanning structures down to a few nanometers.

- **Educators**

  Looking for an AFM to help teach students about AFM operation and applications; and/or looking for an AFM for research projects.

- **Companies**

  Requiring an analytical AFM for applications in product development and process control.

SAMPLE SIZES

Up to 1" x 1" x 3/4"

STANDARD SCANNING MODES

Vibrating (Tapping), Non-Vibrating (Contact), Phase, LFM, F/D

SCANNERS

Three scanners:

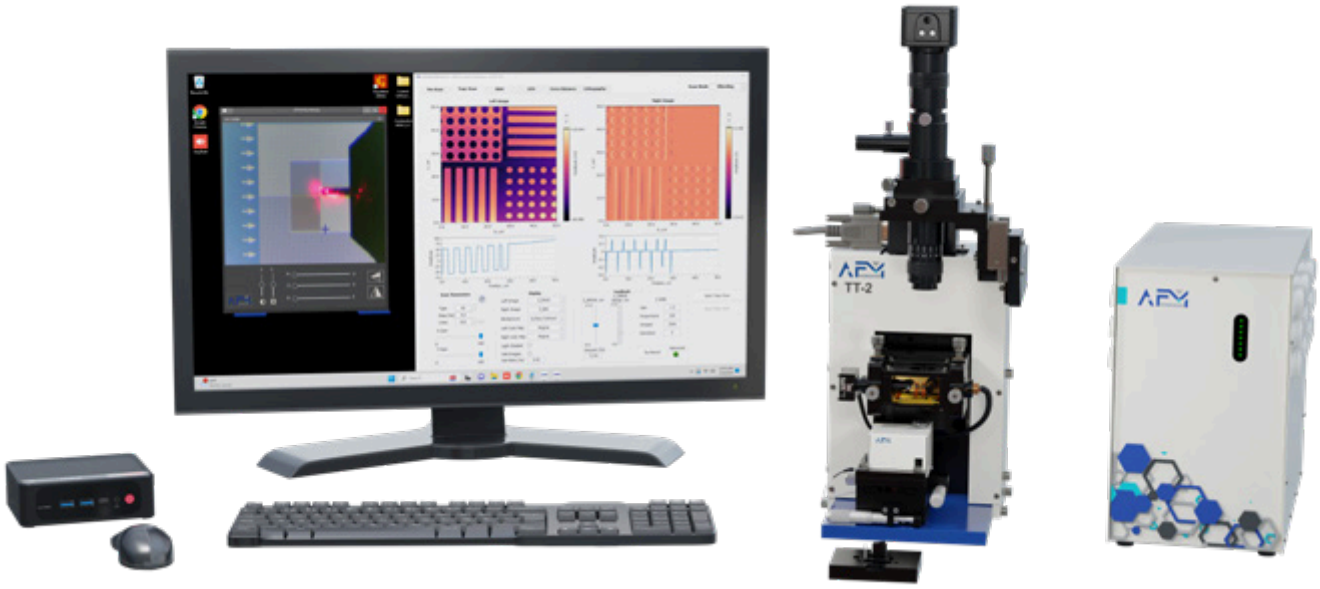
- 15 x 15 x 7µm
- 50 x 50 x 17 µm
- 100 x 100 x 17 µm

VIDEO OPTICAL MICROSCOPES

Zoom to 400X, 2 µm resolution

STAGE AND EBOX SIZE

Compact Tabletop Design



STAGE

The **TT-2 AFM** stage has excellent thermal and mechanical stability required for high resolution AFM scanning. Additionally, its open design facilitates user modification.

RIGID FRAME DESIGN

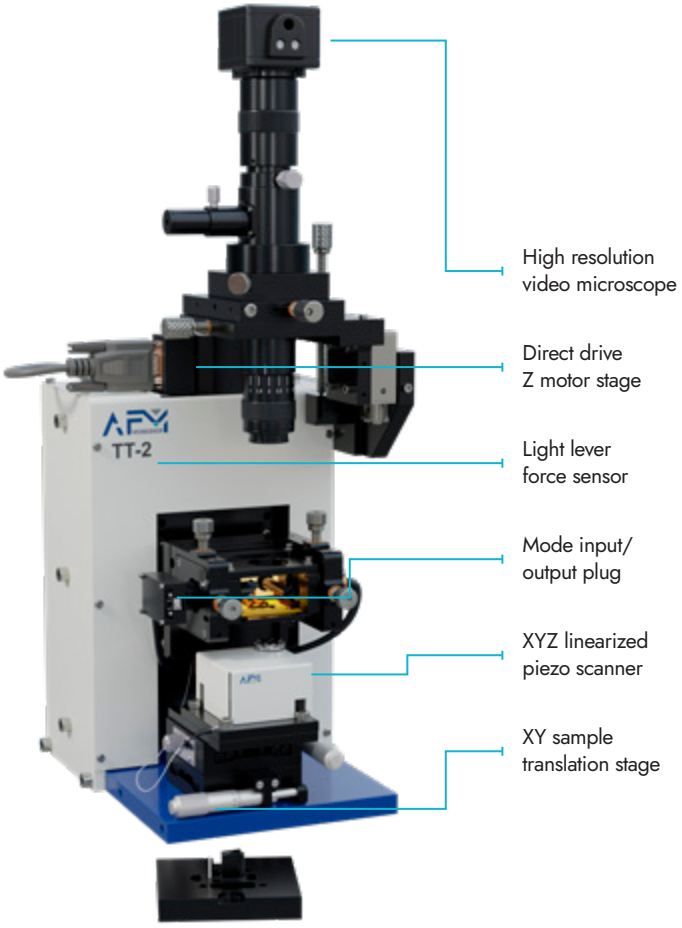
The crossed beam design for the stage support is extremely rigid so the AFM is less susceptible to external vibrations.

LIGHT LEVER AFM FORCE SENSOR

Light lever force sensors are used in almost all AFMs and permit many types of experiments.

INTEGRATED PROBE HOLDER/PROBE EXCHANGER

A unique probe holder and clipping mechanism allows quick and easy probe exchange.



DIRECT DRIVE Z STAGE

A linear motion stage is used to move the probe in a perpendicular motion to the sample. Probe/sample angle alignment is not required, facilitating a much faster probe approach.

SMALL FOOTPRINT

The stage dimensions of 4" X 7" require little space and fit easily on a tabletop.

PRECISION XY STAGE WITH MICROMETER

The sample is moved relative to the probe with a precision XY micrometer stage. Thus, the sample can be moved without touch.

MODES ELECTRIC PLUG

A six pole electrical plug is located at the back of the stage to expand the capabilities of the TT-2 AFM.

XYZ PRECISION PIEZO SCANNER

The modified tripod design utilizes temperature compensated strain gauges which ensure accurate measurements from images. Also, with this design it is possible to rapidly zoom into a feature visualized in an image.

PLD/DETECTOR ALIGNMENT

Both the light lever PLD and the photo detector adjustment mechanism may be directly viewed. This feature simplifies the PLD/detector alignment.

ADAPTABLE SAMPLE HOLDER

At the top of the XYZ scanner is a removable cap that holds the sample. The cap can be modified - or a new cap can be designed – to hold many types of samples.

EBOX

Electronics in the **TT-2 AFM** are constructed around industry standard USB data acquisition electronics. The critical functions, such as XY scanning, are optimized with a 24 bit digital to analog converter combined with 4 bits of gain. With the analog Z feedback loop, the highest fidelity scanning is possible. Vibrating mode scanning is possible with both phase and amplitude feedback using the high sensitivity phase detection electronics.

28-BIT SCANNING

With 28-bit scanning, the highest resolution AFM images may be measured. Feedback control using the XY strain gauges assures accurate tracking of the probe over the surface.

PHASE AND AMPLITUDE DETECTOR CIRCUIT

Phase and amplitude in the Ebox are measured with highly stable phase and amplitude chips. The system can display phase data while using amplitude for feedback when scanning in vibrating mode.

SIGNAL ACCESSIBLE

At the rear of the Ebox is a 50 pin ribbon cable that gives access to all the primary electronic signals without having to open the Ebox.

STATUS LIGHTS

At the front of the Ebox is a light panel that has seven lights. In the unlikely event of a circuit failure, these lights enable determination of Ebox power supply status.

PRECISION ANALOG FEEDBACK

Feedback from the light lever force sensor to the Z piezoceramic is made using a precision analog feedback circuit. The position of the probe may be fixed in a vertical direction with a sample-and-hold circuit.

VARIABLE GAIN HIGH VOLTAGE PIEZO DRIVERS

An improved signal to noise ratio as well as extremely small scan ranges are possible with the variable gain high voltage piezo drivers.

FEATURES:

- Microprocessor for scan generation through 24-bit DACs
- Low-noise, variable gain high-voltage amplifiers with PID feedback for XY scanning
- Dimensions: Width 6" | Height 10" | Depth 14"
- High-fidelity, low noise Z feedback circuits for accurate probe tracking
- Phase and amplitude detection circuits for vibrating mode AFM
- Industry-standard National Instruments USB data acquisition board
- Internally accessible header for signal input/output
- Eight channels of ADC for monitoring and displaying data with LabVIEW™ software

AFM CONTROL SOFTWARE

Software for acquiring images is designed with the industry standard LabVIEW™ programming visual interface instrument design environment. There are many standard functions, including setting scanning parameters, probe approach, frequency tuning, and displaying images in real time.

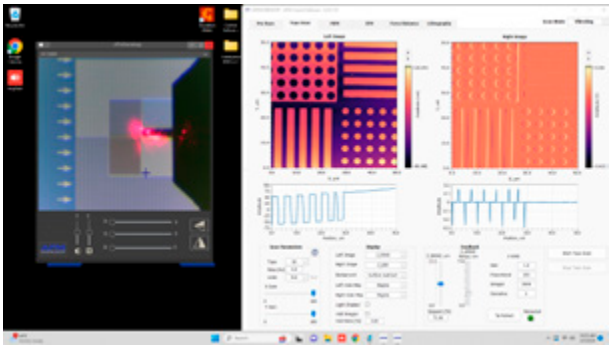
LabVIEW™ facilitates rapid development for those users seeking to enhance the software with additional special features. LabVIEW also enables the **TT-2 AFM** to be readily combined with any other instrument using LabVIEW.

PRE-SCAN TAB

All of the functions required before making a scan are on the pre-scan tab. This includes selecting the scan mode, visual PLD alignment, frequency scan, and automatic tip approach.

TOPO SCAN TAB

Images are acquired using the Topo Scan tab. Parameters selected on the scanning tab include the scan size, scan rate, GPID parameters, and the color scale used for displaying images. Included with the scanning tab is an image buffer capability that facilitates rapid zooming in and out.



AFM CONTROL SOFTWARE CONTINUED...

MODES TABS

Software control for optional modes such as MFM, EFM, and advanced F/D are found in the modes tabs. The example shown here is of the advanced F/D mode tab. This allows fine control of all the parameters controlling acquisition of force-distance curves, as well as acquisition of F-D curve maps.

Mapping of curves in this way allows the user to locate and visualize regions of the sample with differing properties, such as presence of specific molecules, or mechanical properties.

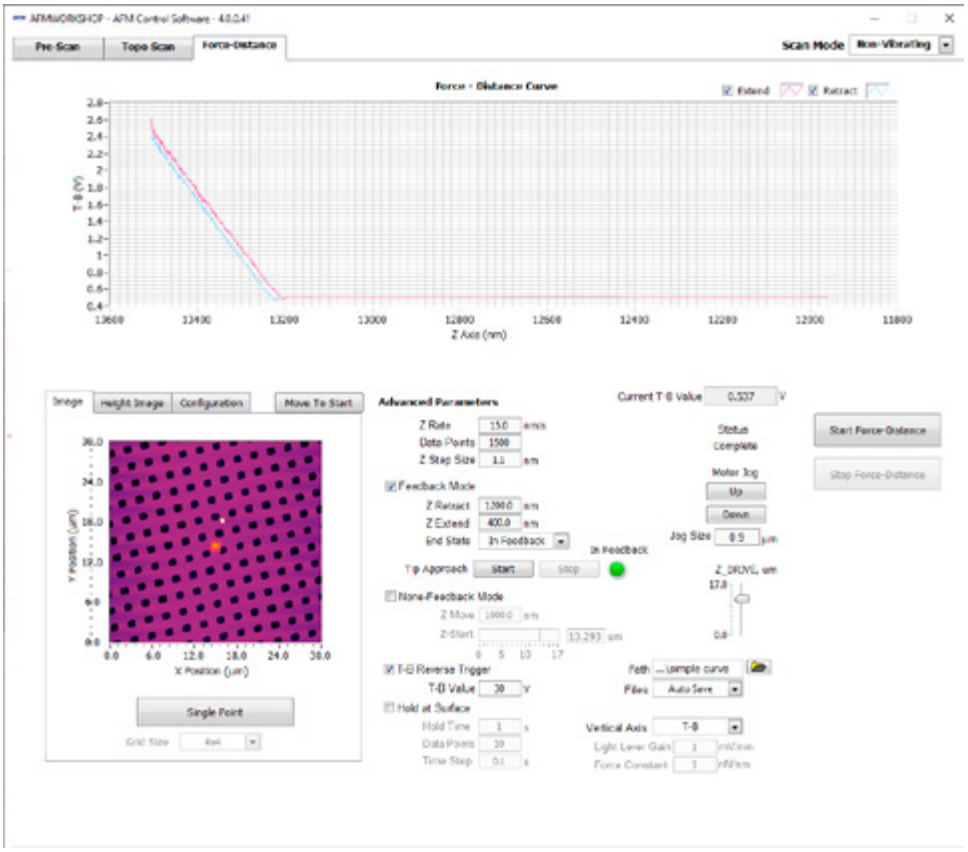
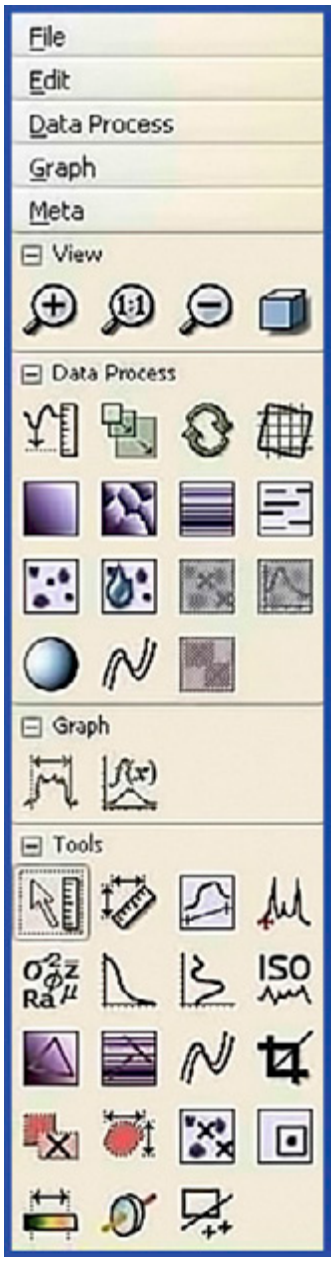


IMAGE ANALYSIS SOFTWARE

Included with the **TT-2 AFM** is Gwyddion open source SPM image analysis software. This complete image analysis package has all the software functions necessary to process, analyze, and display SPM images.

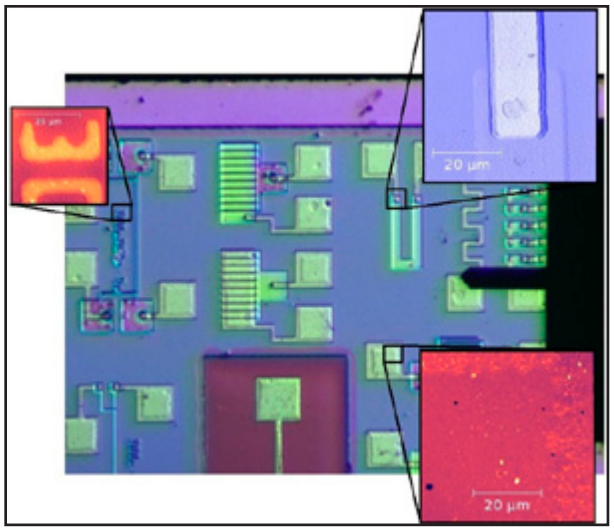


- Visualization: false color representation with different types of mapping
- Shaded, logarithmic, gradient- and edge-detected, local contrast representation, and Canny lines
- OpenGL 3D data display: false color or material representation
- Easily editable color maps and OpenGL materials
- Basic operations: rotation, flipping, inversion, data arithmetic, crop, and resampling
- Leveling: plane leveling, profiles leveling, three-point leveling, facet leveling, polynomial background removal, and leveling along user-defined lines
- Value reading, distance, and angle measurement
- Profiles: profile extraction, measuring distances in profile graph, and profile export
- Filtering: mean, median, conservative denoise, Kuwahara, minimum, maximum, and checker pattern removal
- General convolution filter with user-defined kernel
- Statistical functions: Ra, RMS, projected and surface area, inclination, histograms, 1D and 2D correlation functions, PSDF, 1D and 2D angular distributions, Minkowski functionals, and facet orientation analysis
- Statistical quantities calculated from area under arbitrary mask
- Row/column statistical quantities plots
- ISO roughness parameter evaluation
- Grains: threshold marking and un-marking, and watershed marking
- Grain statistics: overall and distributions of size, height, area, volume, boundary length, and bounding dimensions
- Integral transforms: 2D FFT, 2D continuous wavelet transform (CWT), 2D discrete wavelet transform (DWT), and wavelet anisotropy detection
- Fractal dimension analysis
- Data correction: spot remove, outlier marking, scar marking, and several line correction methods (median, modus)
- Removal of data under arbitrary mask using Laplace or fractal interpolation
- Automatic XY plane rotation correction
- Arbitrary polynomial deformation on XY plane
- 1D and 2D FFT filtering
- Fast scan axis drift correction
- Mask editing: adding, removing or intersecting with rectangles and ellipses, inversion, extraction, expansion, and shrinking
- Simple graph function fitting, and critical dimension determination
- Force-distance curve fitting
- Axes scale calibration
- Merging and immersion of images
- Tip modeling, blind estimation, dilation, and erosion

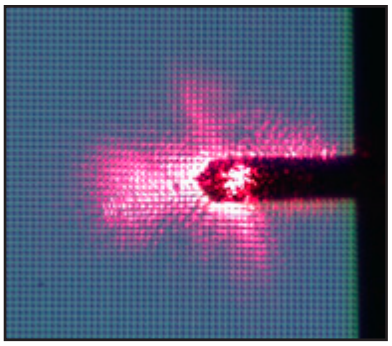
VIDEO MICROSCOPE

A video optical microscope in an AFM serves three functions: aligning the PLD onto the cantilever in the light lever of the AFM, locating surface features for scanning, and facilitating probe approach.

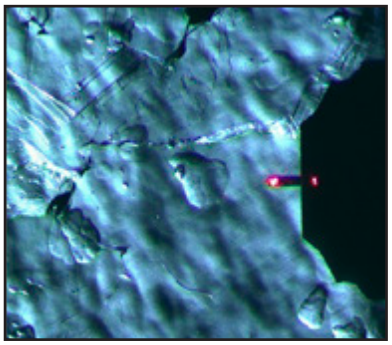
The **TT-2 AFM** includes a high performance video optical microscope along with a 5 megapixel camera, light source, microscope stand, and Windows software for displaying images.



Here the video optical microscope allows viewing features on a test structure. The AFM cantilever is on the right. Three images show results of areas selected for AFM scanning.



PLD alignment is greatly facilitated with the video optical microscope. This vibrating cantilever is 250 µm long. The red spot is from the PLD reflecting off the cantilever.



The video optical microscope zooms out to show an HOPG sample surface and the AFM cantilever.

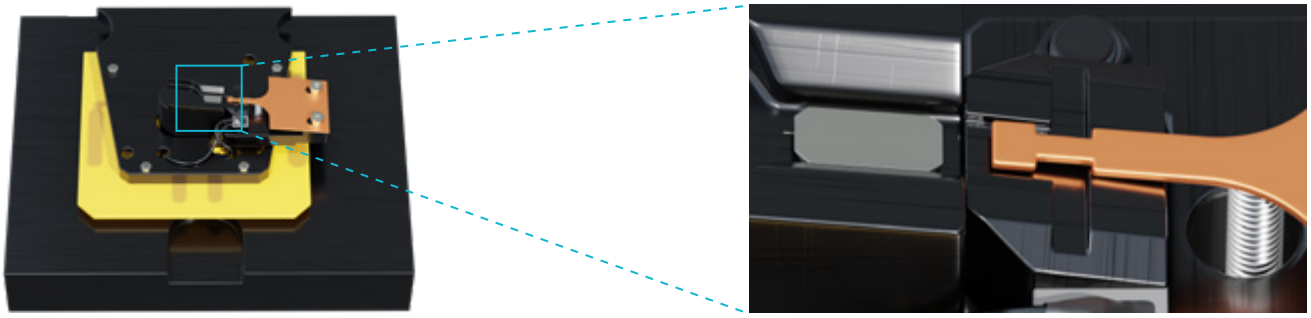
PROBE HOLDER/EXCHANGE

The **TT-2 AFM** utilizes a unique probe holder/exchange mechanism. Probes are held in place with a spring device that mates with a probe exchange tool.

This combination makes changing probes fast and easy on the **TT-2 AFM**.

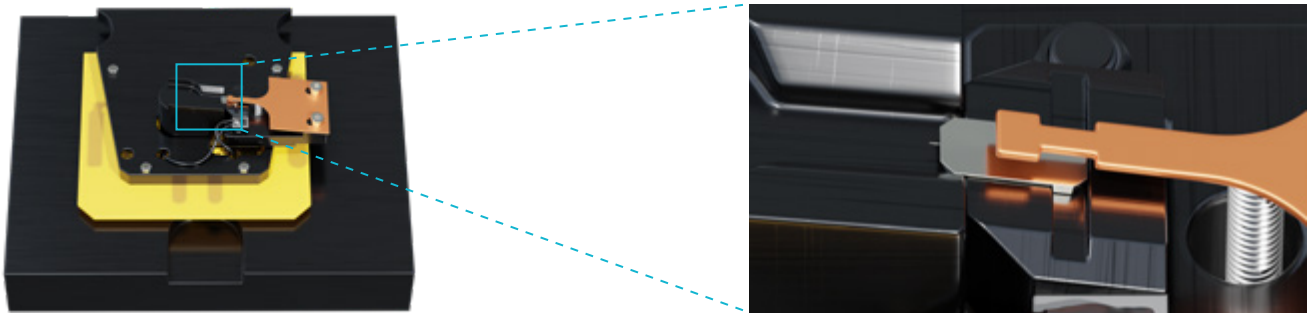
STEP 1

Put probe on exchange tool



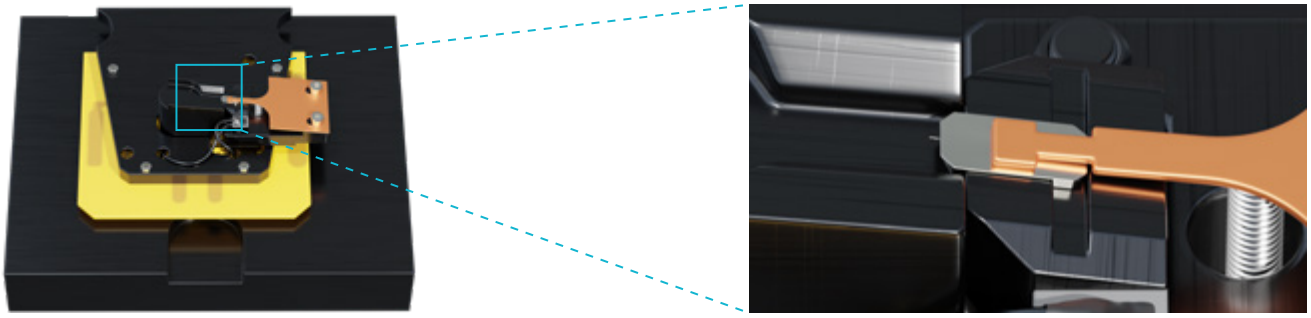
STEP 2

Press down and slide probe into holder



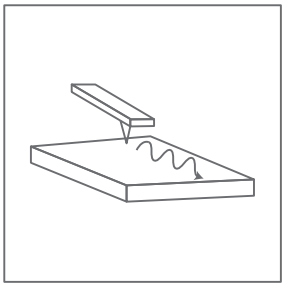
STEP 3

Release spring



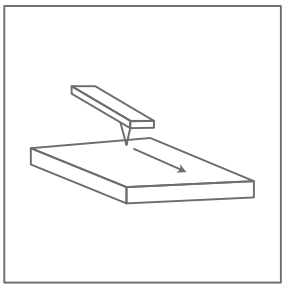
SCANNING MODES

The **TT-2 AFM** includes the MOST COMMONLY USED AFM MODES.
They are:



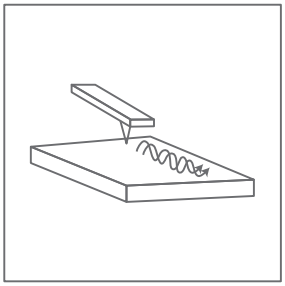
VIBRATING (TAPPING)

Vibrating mode imaging is the most commonly used mode for measuring topography images with an AFM. In vibrating mode the vibration amplitude of the probe is held constant during a scan. Adjustable parameters include the vibrating frequency, amplitude of vibration, and the amount of dampening of the vibrating probe.



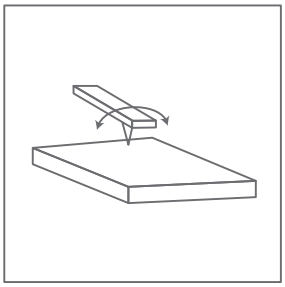
NON-VIBRATING (CONTACT)

In non-vibrating mode, commonly called contact mode, the deflection of a cantilever is held constant during scanning. This mode is often used for scanning in liquids and is also used for measuring force-distance curves.



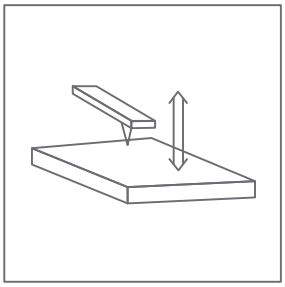
PHASE

Phase mode images are measured in vibrating mode and are useful for identifying different areas of hardness on a surface. The technique operates by measuring the phase change caused by differing materials on a surface while scanning.



LATERAL FORCE

Lateral force mode measures the local friction a probe senses as it is scanned across a surface. The friction can be caused by surface texture and differing chemical composition.

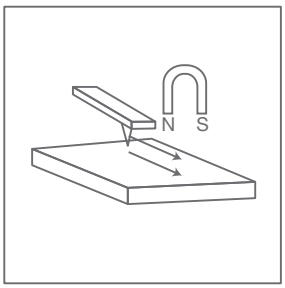


BASIC FORCE/DISTANCE

Force-Distance curves measure the deflection of a cantilever as it interacts with a surface. Force-Distance measurements monitor such surface parameters as: Adhesion, Stiffness, Compliance, Hardness, and Contaminate Thickness. This simple AFM module allows measurements of force-distance curves. It can be upgraded to the Advanced Force-Distance module
(see below).

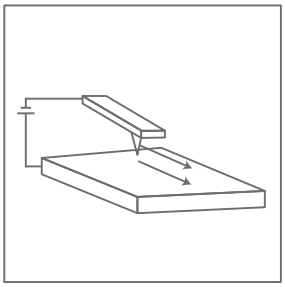
SCANNING MODES CONTINUED...

OPTIONAL MODES that can be purchased with the **TT-2 AFM** include:



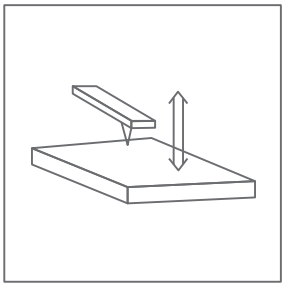
MAGNETIC FORCE

Measures surface magnetic field by incorporating a magnetic probe into the AFM. MFM is used to generate images of magnetic fields on a surface, and is particularly useful in the development of magnetic recording technology. Magnetic fields associated with individual magnetic nanoparticles can also be revealed through MFM.



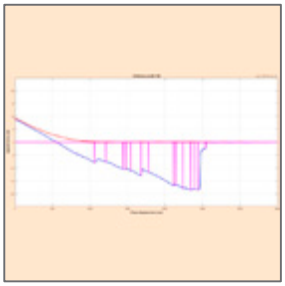
ELECTRIC FORCE

Electrostatic Force Microscopy (EFM) is a type of dynamic non-contact atomic force microscopy where the electrostatic force is probed. "Dynamic" here means that the cantilever is oscillating and does not make contact with the sample. This force arises due to the attraction or repulsion of separated charges.



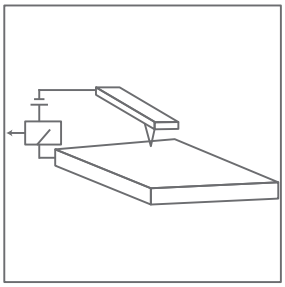
ADVANCED F/D

Force-distance curves measure the deflection of a cantilever as it interacts with a surface. Force-Distance measurements monitor such surface parameters as: adhesion, stiffness, compliance, viscoelasticity, and surface layer thickness. This advanced AFM module is flexible and enables many types of experiments.



FORCE DISTANCE CURVE ANALYSIS SOFTWARE

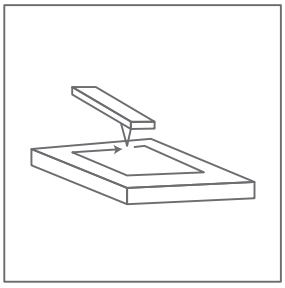
ISFVEM is a fast, intuitive software program for the analysis of a single force distance curve or a grid of curves generated with the AFMWorkshop advanced force distance acquisition software.



CONDUCTIVE AFM

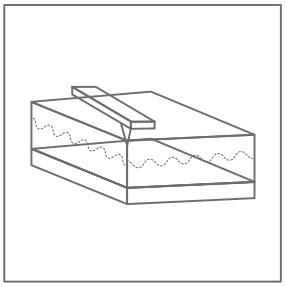
The C-AFM measures topography and conductivity images simultaneously. This option allows measuring current-voltage (I/V) curves at specific locations on a surface. This can be highly useful in development of microelectronics.

SCANNING MODES CONTINUED...



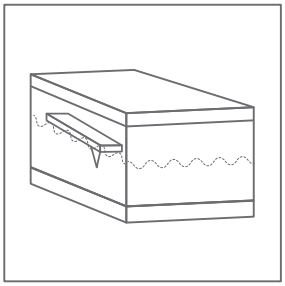
LITHOGRAPHY

This NanoLithography software option enables the AFM probe to alter the physical or chemical properties of the surface. Created in LabVIEW and integrated with the AFM Control software. This software allows the customer to design their own nanolithographic patterns to be written to the sample surface. VI's are available to customers who want to modify the software and create new capabilities.



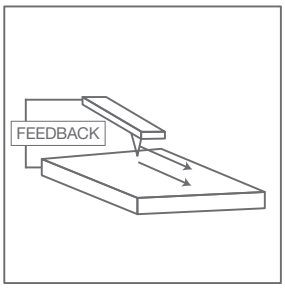
OPEN LIQUID CELL

This option includes a special probe holder and open liquid cell for scanning samples submerged in liquids. The open liquid cell can directly replace the TT-2 AFM probe and sample holder.



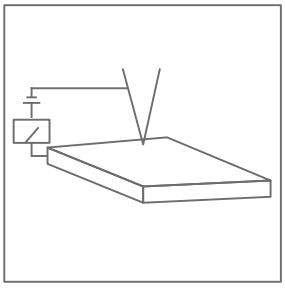
ENVIRONMENTAL CELL (CLOSED LIQUID CELL)

The environmental cell, or closed cell, is used for scanning samples in liquid or gas environments. Both the sample and probe are enclosed in a chamber that has an entry and exit port for the liquid or gas.



SCANNING KELVIN PROBE MICROSCOPY (SKPM)

SKPM measures the potential difference between a conductive probe and a conductive sample. The SKPM measurement is made by monitoring the output of a feedback loop that adjusts the potential on a probe so that the potential difference between the probe and surface is zero.

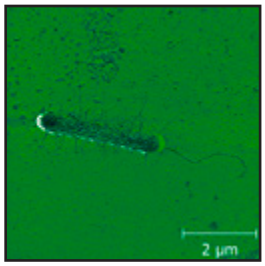


SCANNING TUNNELING

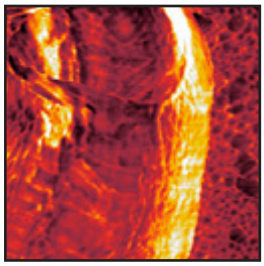
In the STM, the current flow between a metal probe and a sample is used to control the distance between the conductive probe and conductive surface. When the probe is scanned across the surface, if the current between the probe and surface are held constant with a feedback control loop driving a piezo ceramic, the topography of the sample's surface is measured. This also allows measurement of localized I/V curves.

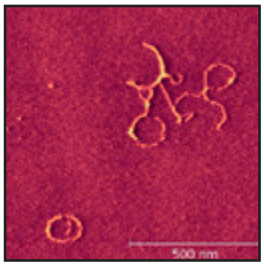
TT-2 AFM IMAGES

With a vertical noise floor of <0.1 nm and a horizontal resolution of 0.08 nm, most types of samples may be imaged with the **TT-2 AFM**. These include hard as well as soft samples.

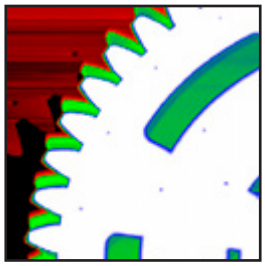


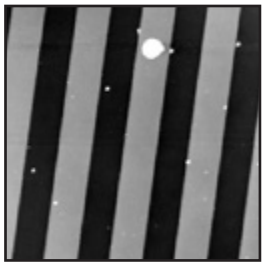
6 x 6 µm, e.coli w/flagellum

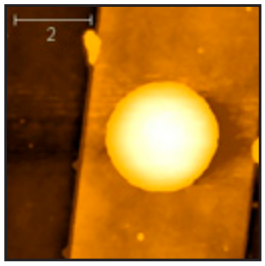

3 x 3 µm, bacteria



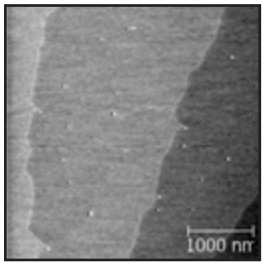
1 x 1 µm, DNA


MEMS multiple level gear

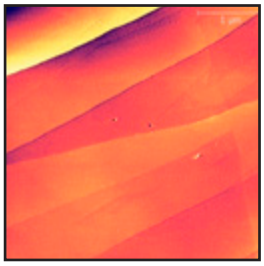

40 x 40 µm, silicon test pattern

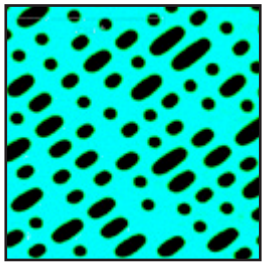


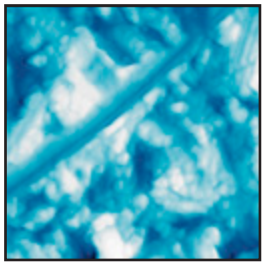
7 x 7 µm, defect

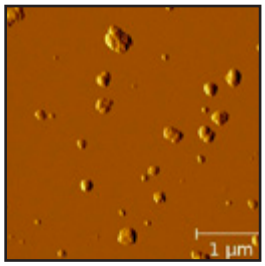


Atomic terraces on Si sample, each terrace is 0.3 nm high

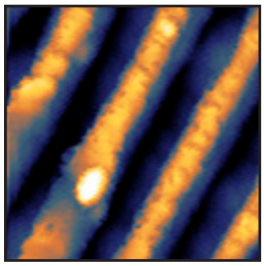

4 x 4 µm, HOPG

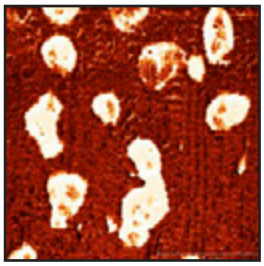

6 µm x 6 µm, DVD


10 x 10 µm, scratch in metal

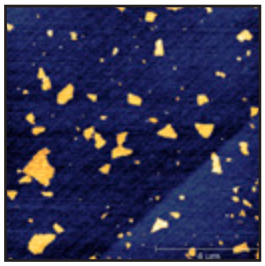


4 x 4 µm, 17 nm nanoparticles


1 x 1 µm, 278 nm test pattern


5 x 5 µm, polymer phase image

25 x 25 µm, parasites


300 x 300 nm, phase PMMA

OPEN DESIGN

An open design is at the core of all products offered by the AFM Workshop. New types of experiments are more readily designed and implemented through the use of LabVIEW™ software. All the mechanical drawings for the **TT-2 AFM** are available in the documentation package option. Finally, the company's website offers a Users Forum to directly share specialized designs developed for the **TT-2 AFM**. For specialized applications, other types of scanners, such as flexure and tubes, can be easily added to the microscope stage.

TT-2 AFM OPTIONS

Although the **TT-2 AFM** comes with everything you need to make AFM images, several additional options are available.
AFMWorkshop regularly develops new options. Contact AFMWorkshop for information on options for the **TT-2 AFM**.

OPTIONAL MODES

Listed on Page 10 and 11 of this data sheet are the optional-modes available for the TT-2 AFM.

ELECTRICAL MODES

- Conductive AFM (C-AFM)
- Scanning Kelvin Probe (SKPM)
- Electric Force Microscopy EFM)
- Scanning Tunneling (STM)

LIQUID MODES

- Dunk and Scan - Open Liquid Cell
- Environmental Cell

OTHER MODES

- Lithography
- Advanced Force/Distance
- Magnetic Force
- Force Distance Curve Analysis Software

OPTIONAL FEATURES

Image Logger

This option allows display of six channels in the forward and reverse direction. It has a spectrum function as well as a six channel data logger.

Break Out Box

BNC gives access to most of the signals in the Ebox.

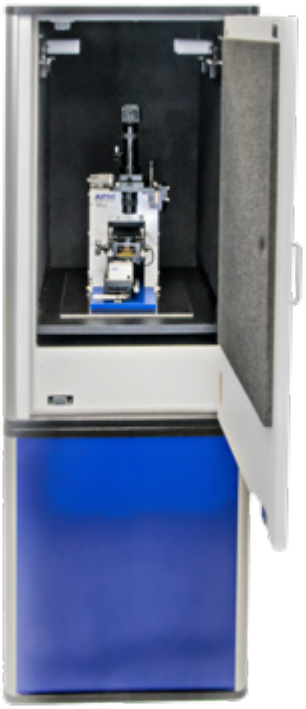
Scanners

There are three scanners available for the TT-2 AFM. They are:

- 15 x 15 x 7µm
- 50 x 50 x 17 µm
- 100 x 100 x 17 µm

Q-Box/Q-Base

The Q-Box is a unique vibration solution that reduces both sound and structural vibrations. It features a unique adjustable elastomer suspension system which is optimal for atomic force microscopes.



SPECIFICATIONS

SCANNER SPECIFICATIONS	100 × 100 × 17	50 × 50 × 17	15 × 15 × 7
Engineering Specifications			
◆ XY Resolution	0.010 nm	0.005 nm	0.003 nm
◆ XY Linearity	<0.1%	<0.1%	<0.1%
◆ Z Resolution	0.003 nm	0.003 nm	0.0015 nm
◆ Z Linearity	<0.1%	<0.1%	<0.1%
Performance Specifications			
◆ XY Range	100 µm	50 µm	15 µm
◆ XY Linearity	<1%	<1%	<1%
◆ XY Resolution			
» Closed Loop	<6 nm	<3 nm	<1 nm
» Open Loop	<1 nm	<1 nm	<0.3 nm
◆ Z Range	17 µm	17 µm	7 µm
◆ Z Linearity			
» Open Loop	<5%	<5%	<5%
» Closed Loop	<1%	<1%	<1%
◆ Z Sensor Noise	1 nm	1 nm	N.A.
◆ Z Feedback Noise	<0.2 nm	<0.2 nm	<0.1 nm
Actuator Type	Piezo	Piezo	Piezo
Design	Modified Tripod	Modified Tripod	Modified Tripod
XY Sensor Type	Strain Gauge	Strain Gauge	Strain Gauge
Z Sensor Type	Strain Gauge	Strain Gauge	N.A.

Electronic Control Specifications			
◆ XY Scan	2 × 28 bits	24-bit scan DAC, 4-bit gain	192 KHz
◆ XY Linearizion Control	2 × 24 bits	24 bit ADC	192 KHz
◆ Z Axis Control	Analog	4 amplifier – GPID	1 microvolt noise
◆ Input Signal Bandwidth	5 MHz		
◆ Z Axis Signal Capture	20 bits	16-bit ADC, 4-bit gain	50 KHz
◆ Phase Signal Capture	2 × 16 bits	ADC	50 KHz
◆ L-R Signal Capture	2 × 16 bits	ADC	50 KHz
◆ Amplitude Signal Capture	2 × 16 bits	ADC	50 KHz
◆ Z Error Signal Capture	2 × 16 bits	ADC	50 KHz
◆ Main Controller MPU	80 MHz/105 DMIPS, 32 Bits (5-stage pipeline, Harvard architecture)		
◆ Excitation/Modulation	Analog PLL	0-800 KHz	
◆ Communication		USB 2.0	
◆ Signal capture specified includes the image logger option. Without Image Logger 1 X 16 bits			

Optional Electronics Specifications			
◆ User Input Signal (1)	32 × 18 bits	ADC	625 KHz
◆ User Output (1)	32 × 18 bits	DAC	625 KHz
◆ User Monitor(1)	48 Lines	Digital IO	MHz
◆ Optional Controller MPU (2)	80 MHz/105 DMIPS, 32 Bits (5-stage pipeline, Harvard architecture)		

(1) Optional User I/O upgrade

(2) Used for MFM, PhotoCorrect, EFM

SPECIFICATIONS CONTINUED...

SOFTWARE

Environment	LabVIEW™
Operating System	Windows
Image Acquisition	Real Time Display (2 of 8 channels)

STAGE SPECIFICATIONS

Light Lever	
PLD Motion	XY ± 1.5 mm · Z 2 mm
Detector Motion	XY ± 1.5 mm · Z 7 mm
Sample Translator	
XY Range	30 mm
Resolution	2 microns
Z Approach Translator	
Range	30 mm
Resolution	330 nm
Z Sample Size	
Thickness	19 mm
Probe Accessible Area	25 x 25 mm
Maximum Size	75 x 75 mm

CONTROL PARAMETERS

GPID Z Feedback Control	Yes
GPID XY Feedback control	Yes
Setpoint	Yes
Scan Range	Yes
Scan Rate	Yes
Image Rotate	0° to 360°
PLD Align T-B, L-R, T+B	Yes
Vibrating Freq. Display	Yes
Force Distance	Yes
Automated Tip Approach	Yes
Oscilloscope, Y-Z	Yes
Image Store Format	Industry Standard
Image Pixels	16 × 16 to 1024 × 1024
H.V. Gain Control	XY and Z
Real Time Display	Line Level, Histogram, Multiple False Color Pallets
Calibration	System Window
Jog Up - Jog Down	Yes
Image Buffers	12

VIDEO OPTICAL MICROSCOPE SPECIFICATIONS

- Top-view Optic:
  - Research Grade
  - Mechanical 7:1 Zoom Ratio
  - 5 MegaPixel CMOS Camera
  - 114 mm Working Distance
  - On-axis LED Light

PHYSICAL SPECIFICATIONS

Stage	
Weight	20 lbs
Dimensions	10″ × 8″ × 19″
Ebox	
Weight	6 lbs
Dimensions	6″ × 14″ × 10.5″
Power	< 250 W
Voltage	110 V/220V